

03560.002760.



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Shuichi YABU

Application No.: 09/811,447

Filed: March 20, 2001

For: EXPOSURE APPARATUS, GAS
REPLACING METHOD, AND METHOD
OF MANUFACTURING A
SEMICONDUCTOR DEVICE

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) Examiner: A. Mathews

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) Group Art Unit: 2851

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) Allowed: February 28, 2003

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) Confirmation No.: 9561

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:
) May 28, 2003

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to further examination on the merits, please amend the above-identified application
as follows:

INTRODUCTORY COMMENTS

This Amendment has been prepared in accordance with the Revised Format established
by the U.S. Patent and Trademark Office, as permitted in the Pre-OG Notice dated February 4,
2003, and entitled "Amendments in a Revised Format Now Permitted."